

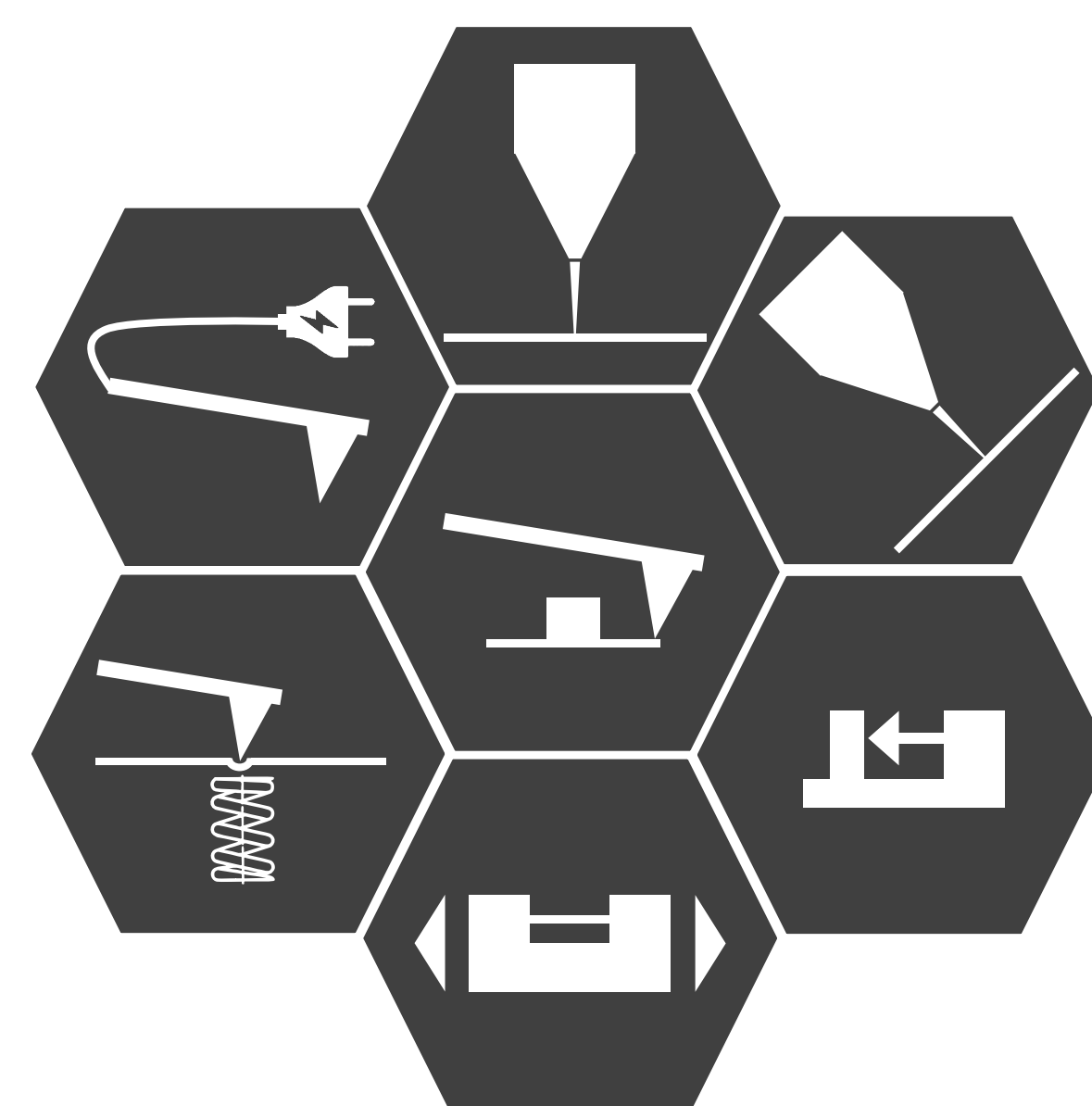
Improved Understanding of Material Behavior using Correlative In-Situ Techniques

The AFSEM™ concept



AFSEM™ correlated microscopy

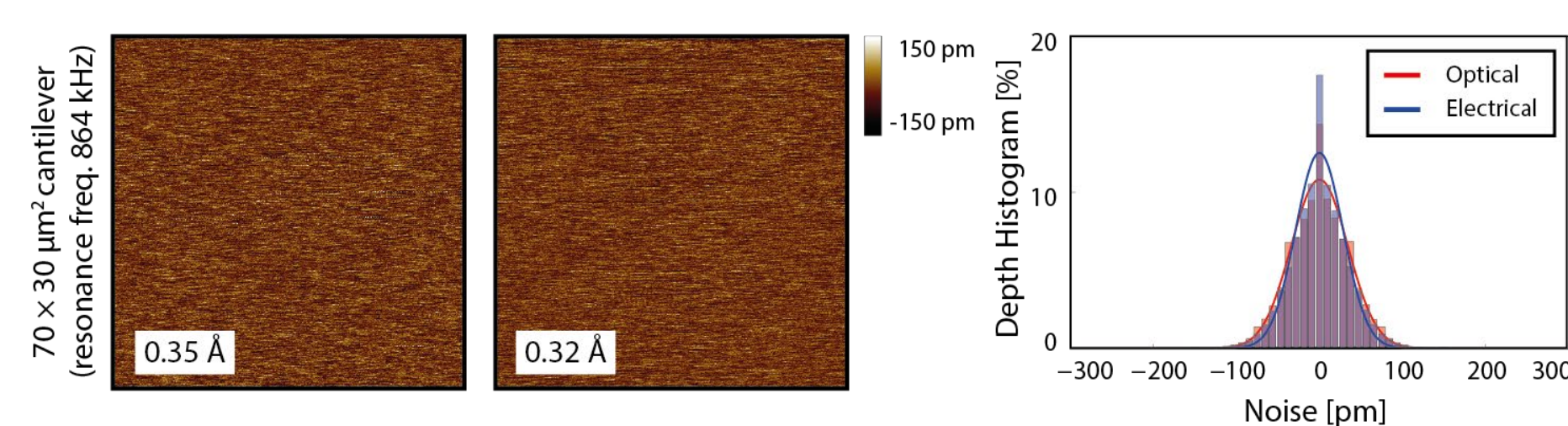
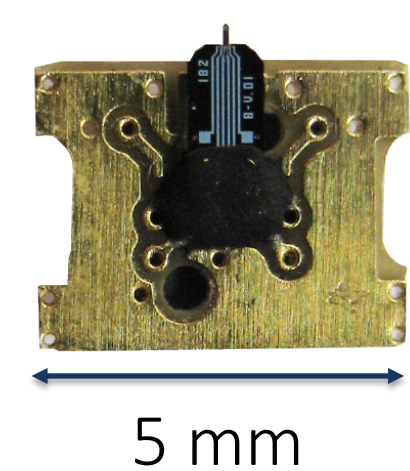
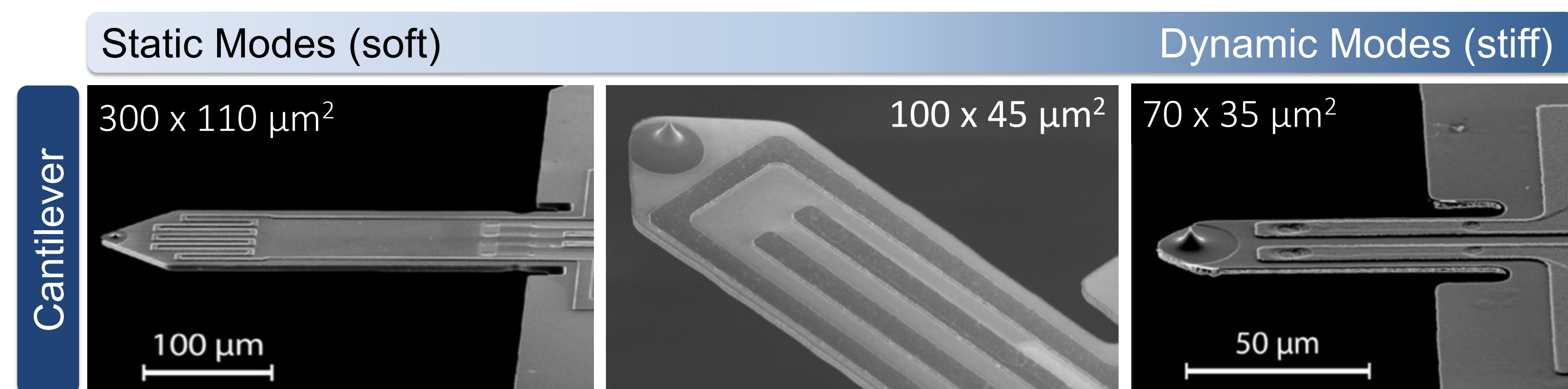
AFSEM™ is a novel AFM platform specifically designed and developed for integration into other host systems, such as SEM or Dual-beam (SEM/FIB) microscopes. Its open design allows to simultaneously operate SEM/FIB and AFSEM™ inside the SEM/FIB vacuum chamber.



Main benefits:

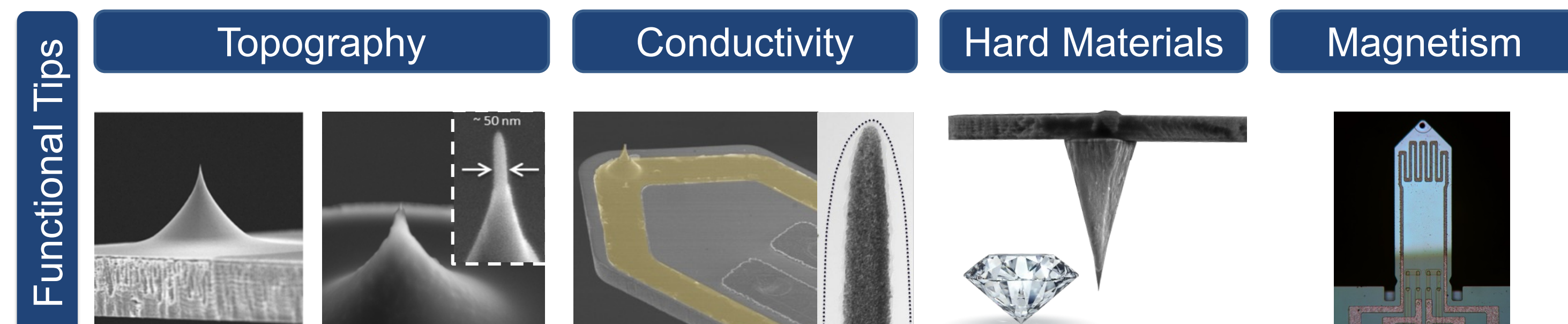
- **Direct 3D information** with sub-nanometer resolution
- **Correlative Microscopy** at highest SEM resolution of exactly the same sample position by SEM/FIB, EDX and AFSEM™
- **No air exposure of the sample** during interactive analysis by different methods
- **Nanometer Scale Analysis** before SEM sample contamination
- **Ease of Use** – No AFM laser alignment due to self-sensing cantilever technology
- AFSEM™ accepts **any Sample** the host system accepts

Self-Sensing Cantilever Technology

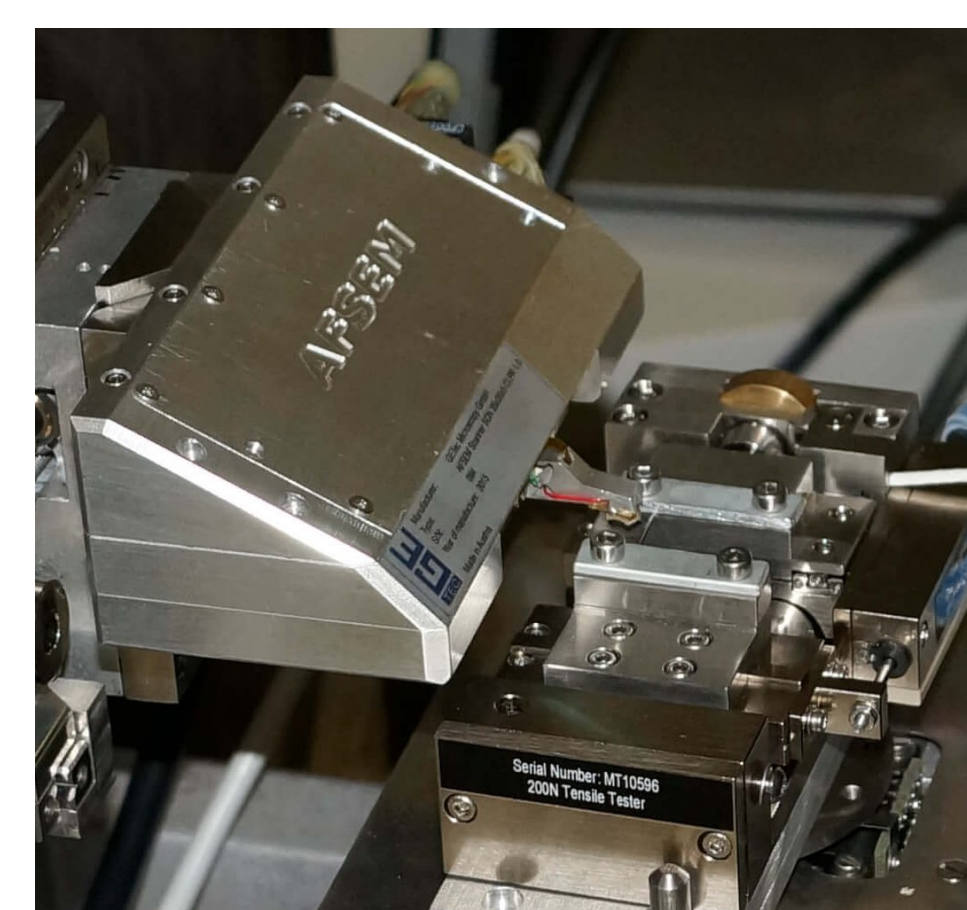


Electrical Noise Level of 0.32 Å for Self-Sensing Cantilever equals Optical Noise Level

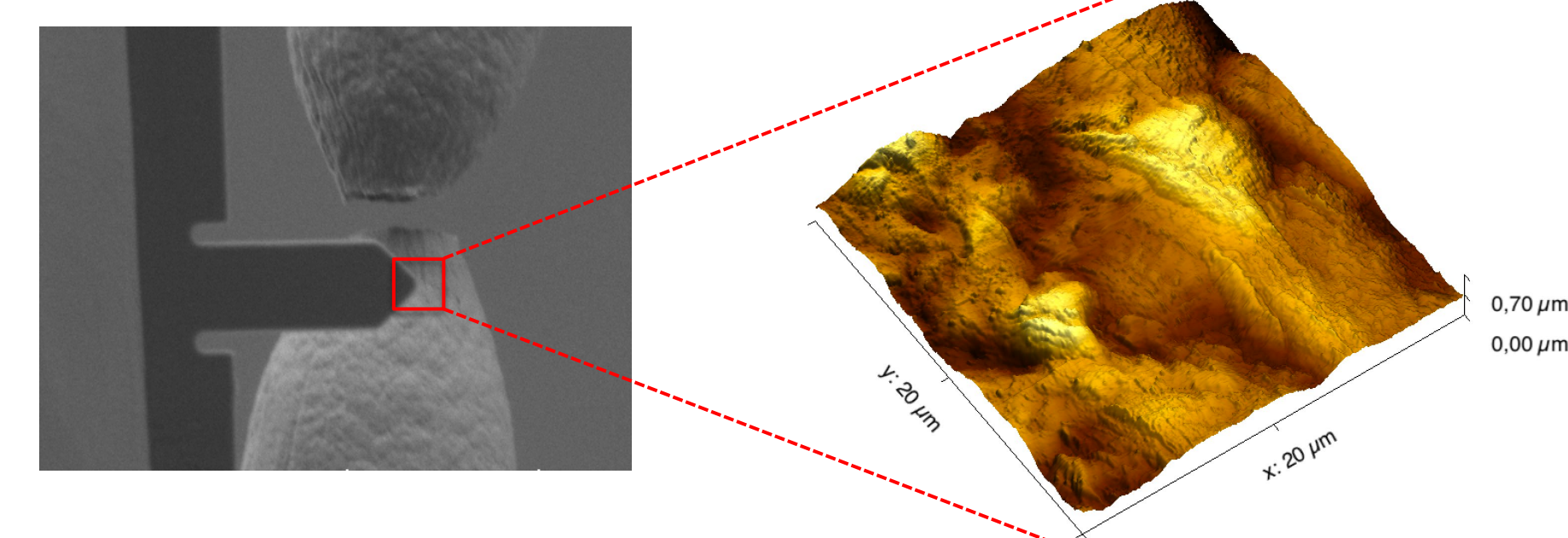
M. Dukic, J. D. Adams and G. E. Fantner. *Scientific Reports* **5**, 16393 (2015)



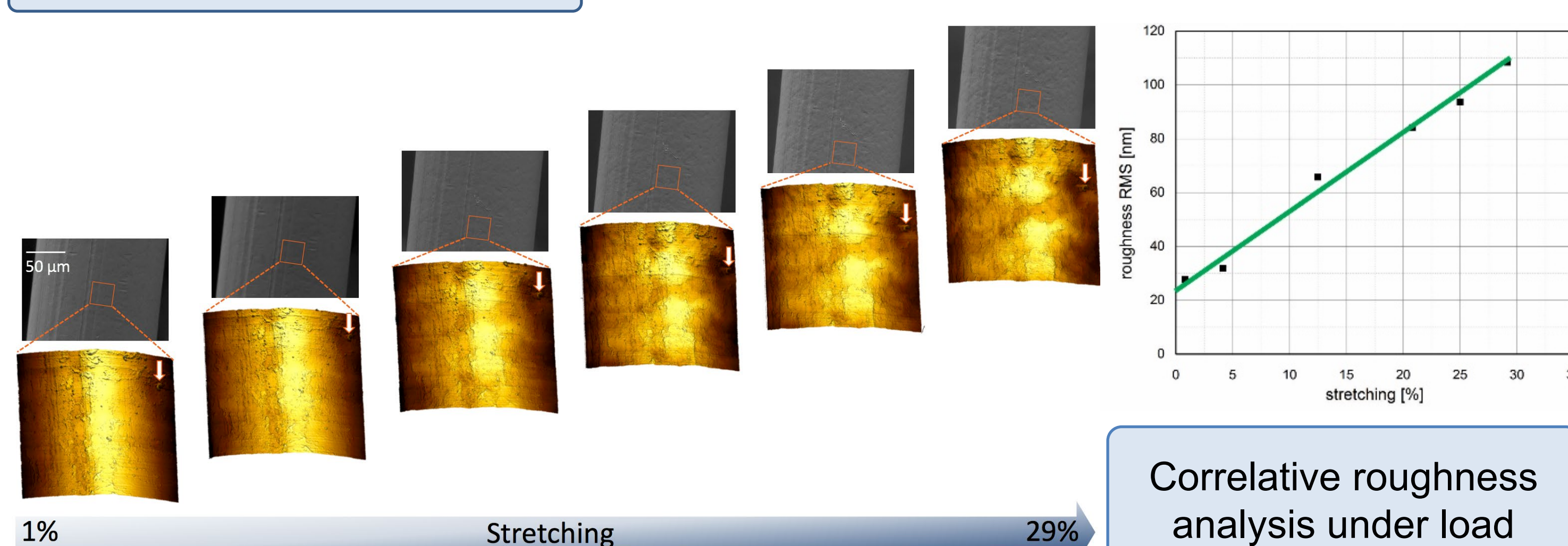
In-Situ Micro-Mechanical Testing



Combine **SEM**, tensile stage and **AFSEM™**



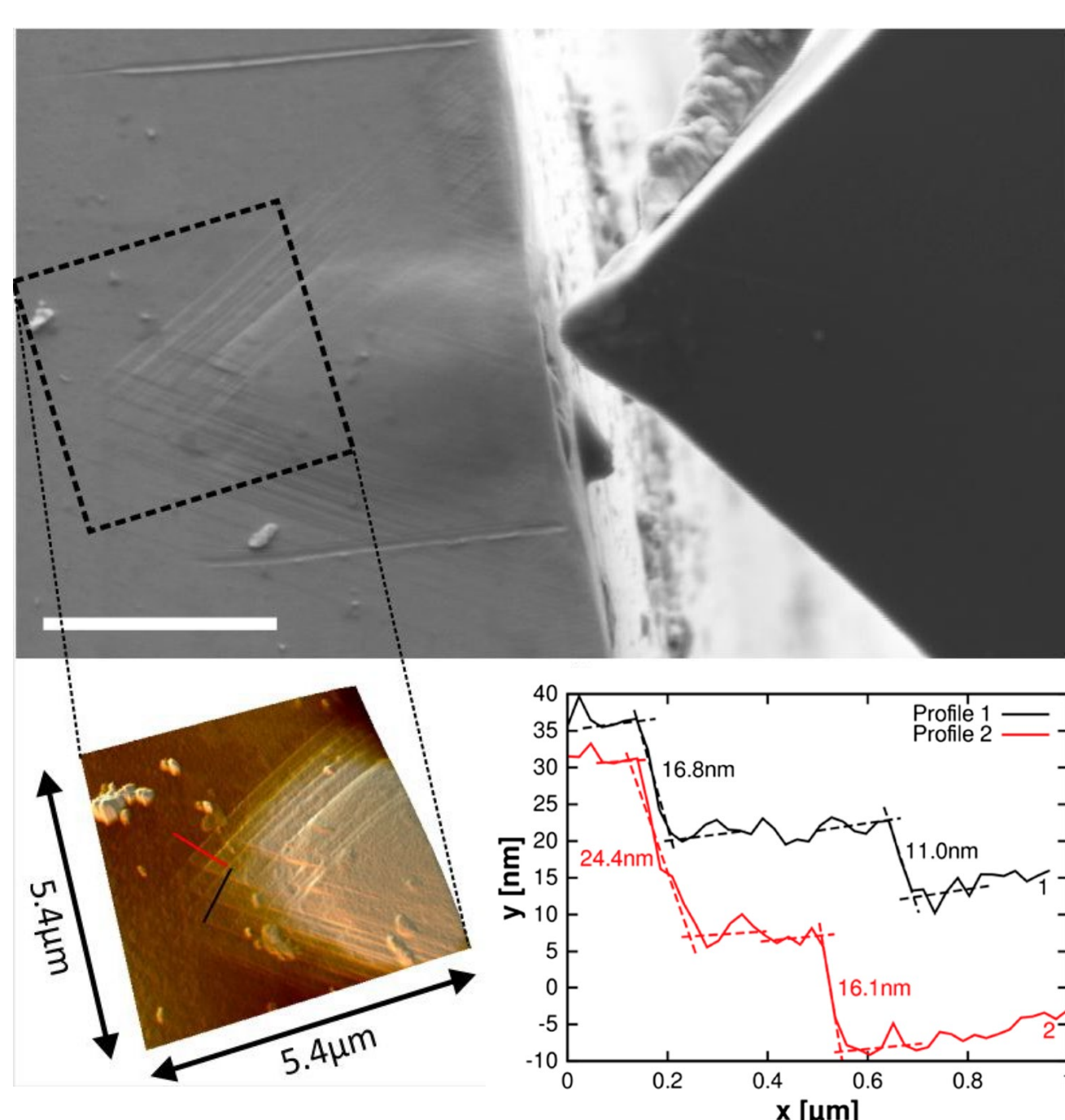
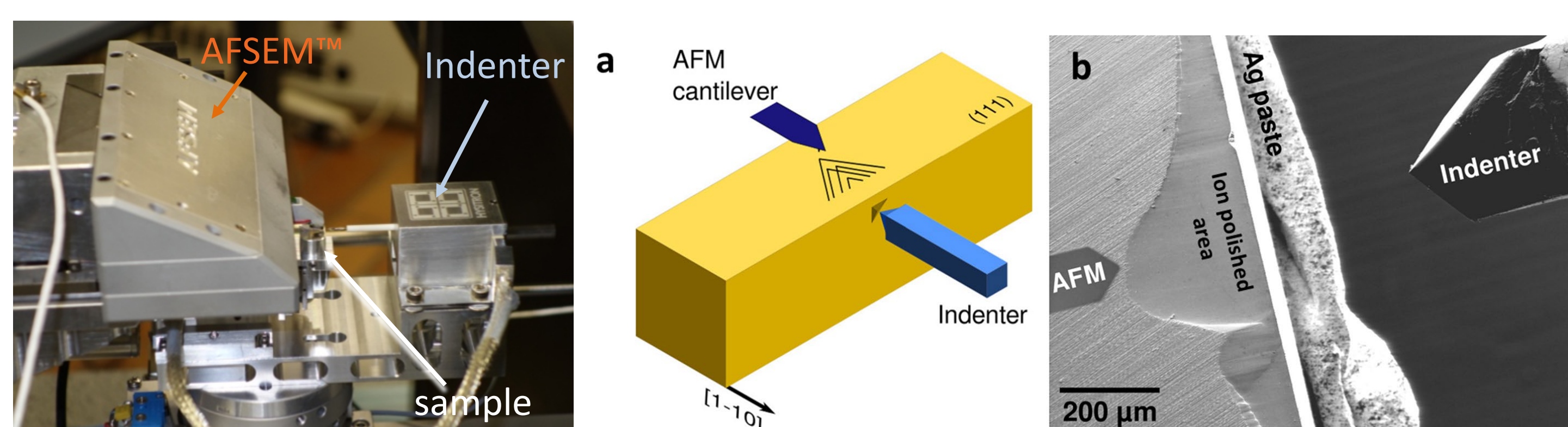
Observe sample changes with **SEM**, measure details with **AFSEM™**



Correlative roughness analysis under load inside the SEM

Correlative Nanoindentation Analysis

Combine **SEM**, nano-indenter and **AFSEM™** for **correlative in-situ** experiments

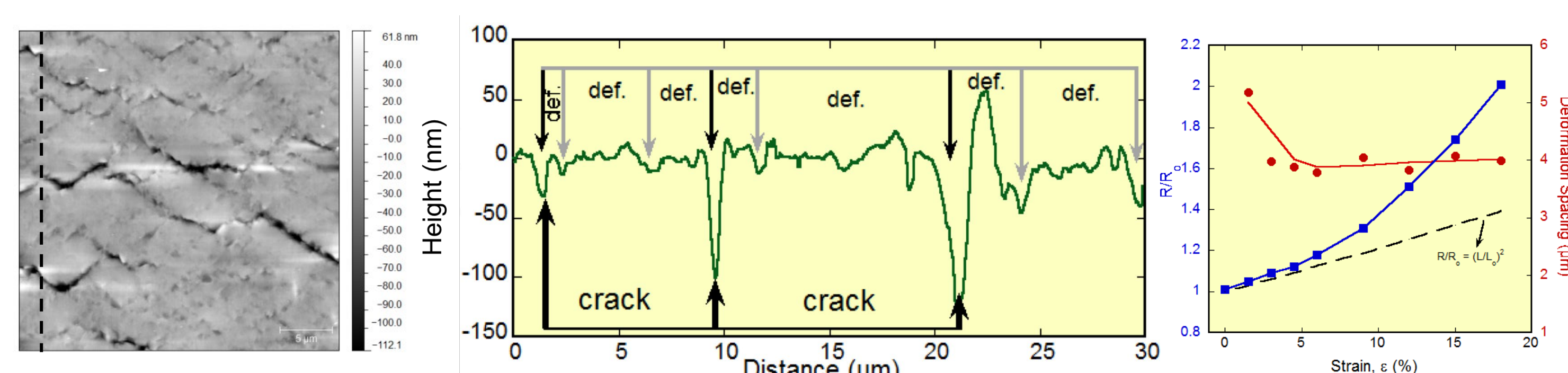


- Investigate evolution of slip-step dynamics with sub-nanometer resolution
- Analyze your sample before SEM contamination or oxidation effects
- Quantify the number of emitted dislocations exactly at the area of interest

J. Kreith et al., *Rev. Sci. Instrum.* **88**, 053704 (2017)

Mechanical Testing of Flexible Electronics

Combine **SEM**, **AFM** and **in-situ** 4-point-probe measurements to study flexible electronics during straining



Measure **in-situ** 3D-topography AND conductivity

